

THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Davis et al.

10/665,934

Filed:

Serial No.:

September 19, 2003

Confirmation No.: 6821

For: Method of Controlling Critical Dimension Microloading of **Photoresist Trimming Process** by Selective Sidewall Polymer

Deposition

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Group Art Unit: 2812

Examiner:

MAIL STOP AMENDMENT Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

CERTIFICATE OF MAILING 37 CFR 1.8

I hereby certify that this correspondence is being deposited on August 3, 2004 with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450 Alexandria, YA 22313-1450.

PRELIMINARY AMENDMENT

Prior to examination, please amend the above-identified application as follows:

Amendments to the Specification begin on page 2 of this paper. Amendments to the claims are reflected in the listing which begins on page 5 of this paper. Remarks begin on page 8 of this paper.